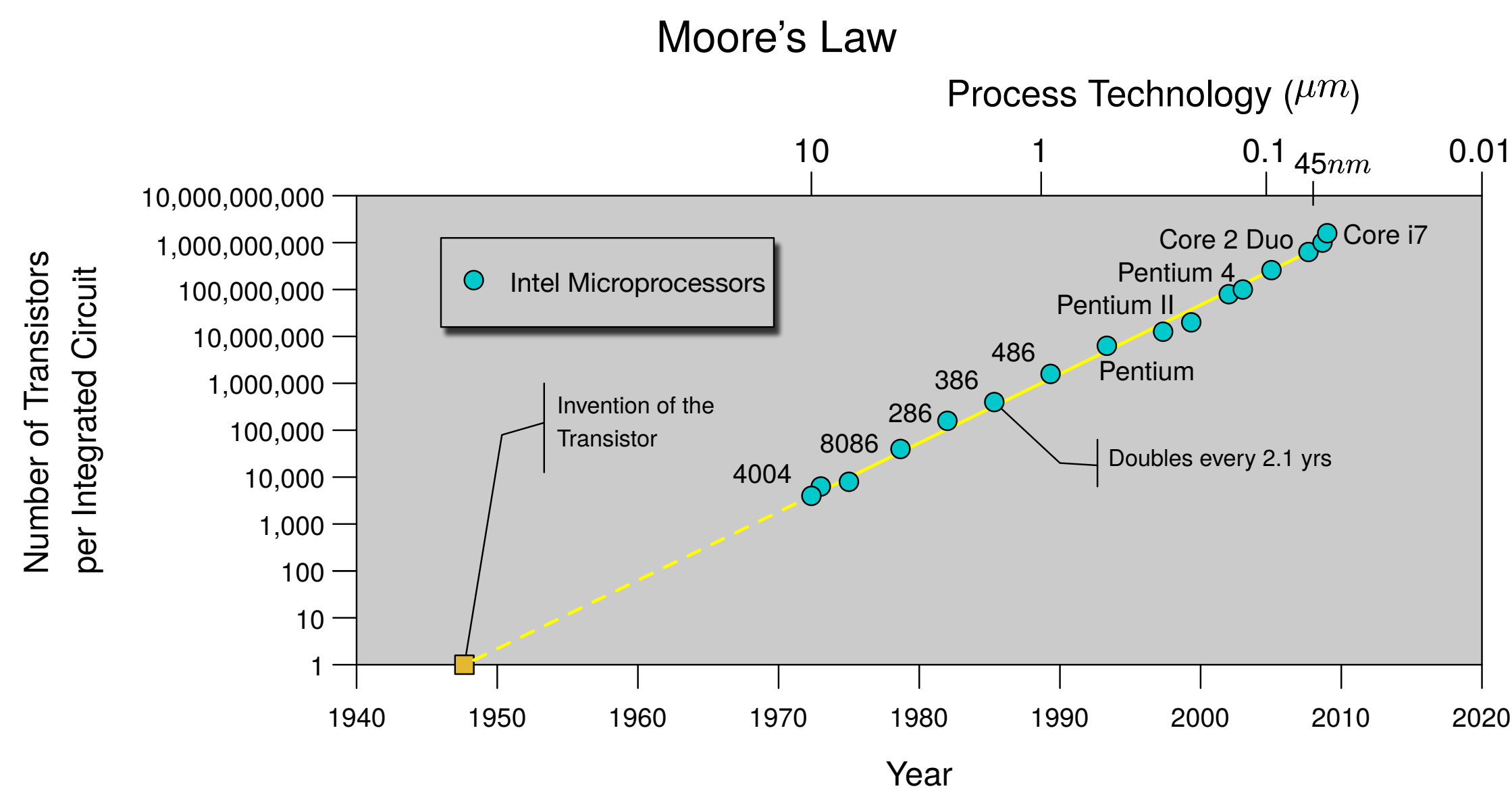




Backgrounds

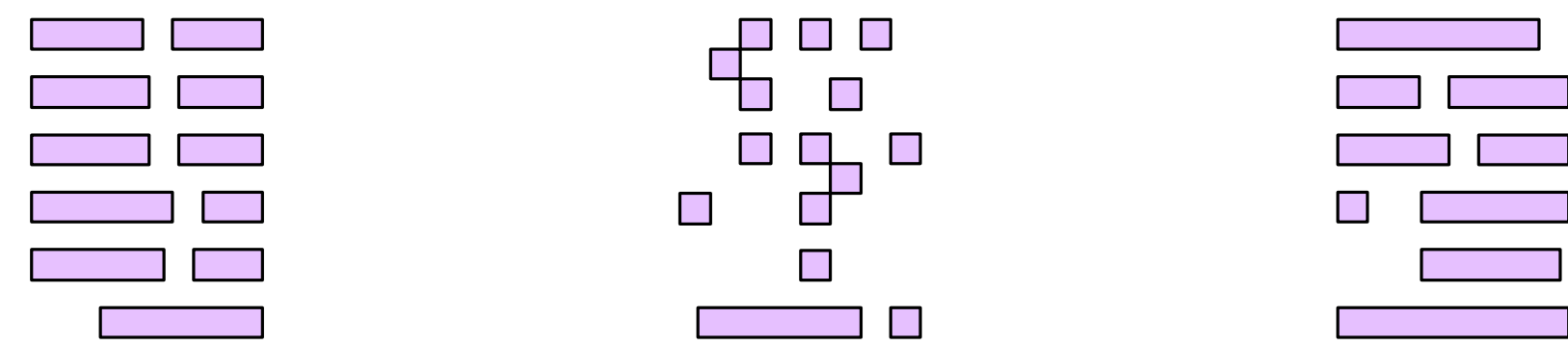
Moore's Law to Extreme Scaling



EUV Brings Challenges in DFM

- Hotspot detection and fix
 - Previous researches show the significance of a diverse and balanced training data set. [Yang+, SPIE'17]
 - Hotspot pattern library covering the design space required by machine learning and pattern matching solutions.
 - Lithographic simulation challenge due to complicated computational lithography model under EUV nodes. [Levinson+, SPIE'18]
- Early technology node development
 - Due to long logic to layout cycle, test layout patterns are not usually available.
 - OPC convergence problem.
 - Patterns are required to massage Design rule, OPC recipe, ...

Related Works on Pattern Generation

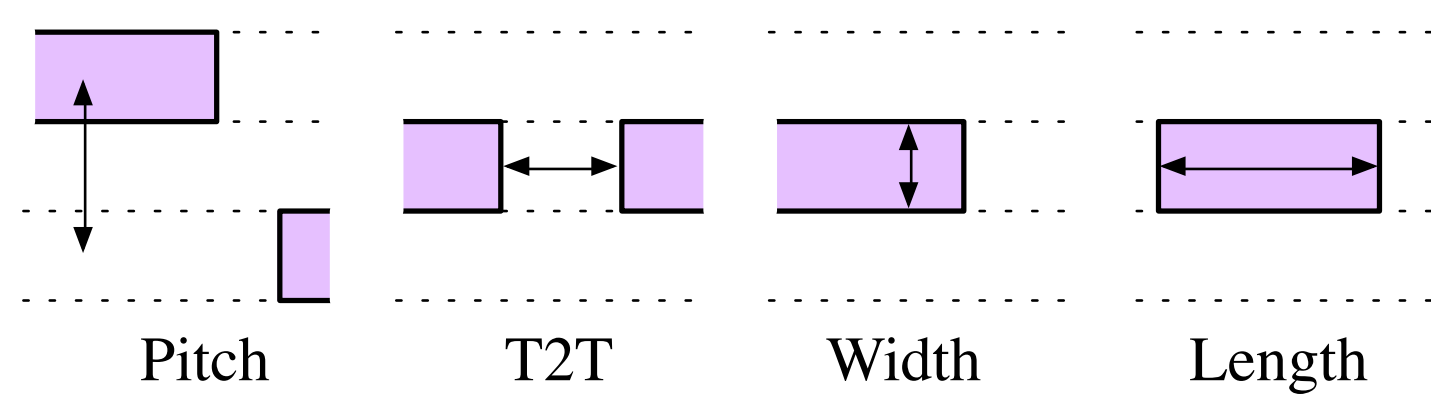


- Transferring from previous technology node. (not applicable for large technology node gap) [Zhuang+, ICSICT'16]
- Randomly placing patterns according to certain constraints. (limited diversity)
- Generative machine learning models. (violating design rules) [Alec+, ICLR'16]

Preliminaries

Pattern Generation Challenges

- 7nm EUV metal layer unidirectional on-track shapes.
- Pitch, denoted as p , measures the distance between two adjacent tracks that contain shapes.
- T2T, denoted as t , measures the line-end-to-line-end distance between two adjacent shapes in a track.
- Wire length l and width w measure the shape size along and against the design track.



Evaluation of Pattern Library

All shape edges in a fixed-size window are aligned with x -axis and y -axis. If we extend all horizontal and vertical edges infinitely into scan lines, more non-overlapping scan lines always come with more complex patterns. We hence define the complexity of a layout pattern as follows.

- Pattern Complexity.** The complexity of a pattern in x and y directions (denoted as c_x and c_y) are defined as the number of scan lines subtracted by one along x -axis and y -axis, respectively.

We also introduce the concept of *pattern diversity* (denoted as H) to measure how are the pattern complexities distributed in a given library. A larger H implies the library contains patterns that are more evenly distributed, as in the following definition.

- Pattern Diversity.** The diversity of a pattern library is given by the *Shannon Entropy* of the pattern complexity sampled from the library,

$$H = - \sum_i \sum_j P(c_{xi}, c_{yj}) \log P(c_{xi}, c_{yj}),$$

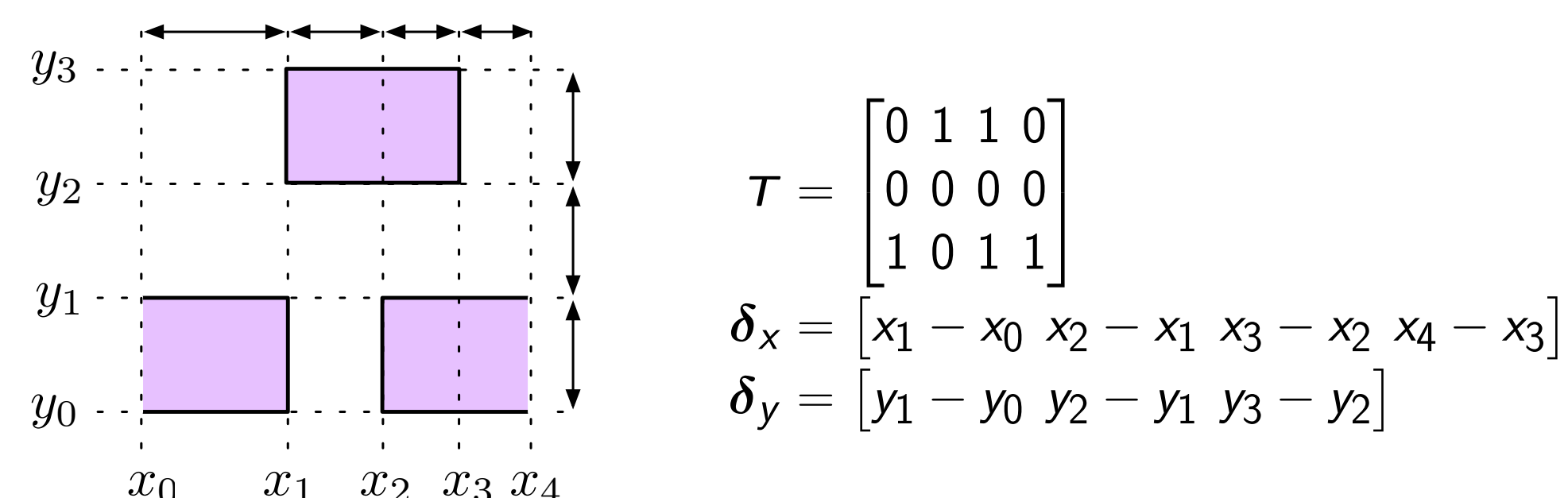
where $P(c_{xi}, c_{yj})$ is the probability of a pattern sampled from the library has complexities of c_{xi} and c_{yj} in x and y directions respectively.

Problem (Pattern Generation)

Given a set of layout design rules, the objective of pattern generation is to generate a pattern library such that the pattern diversity and the number of unique DRC-clean patterns in the library is maximized.

Methods

Squish Representation Example



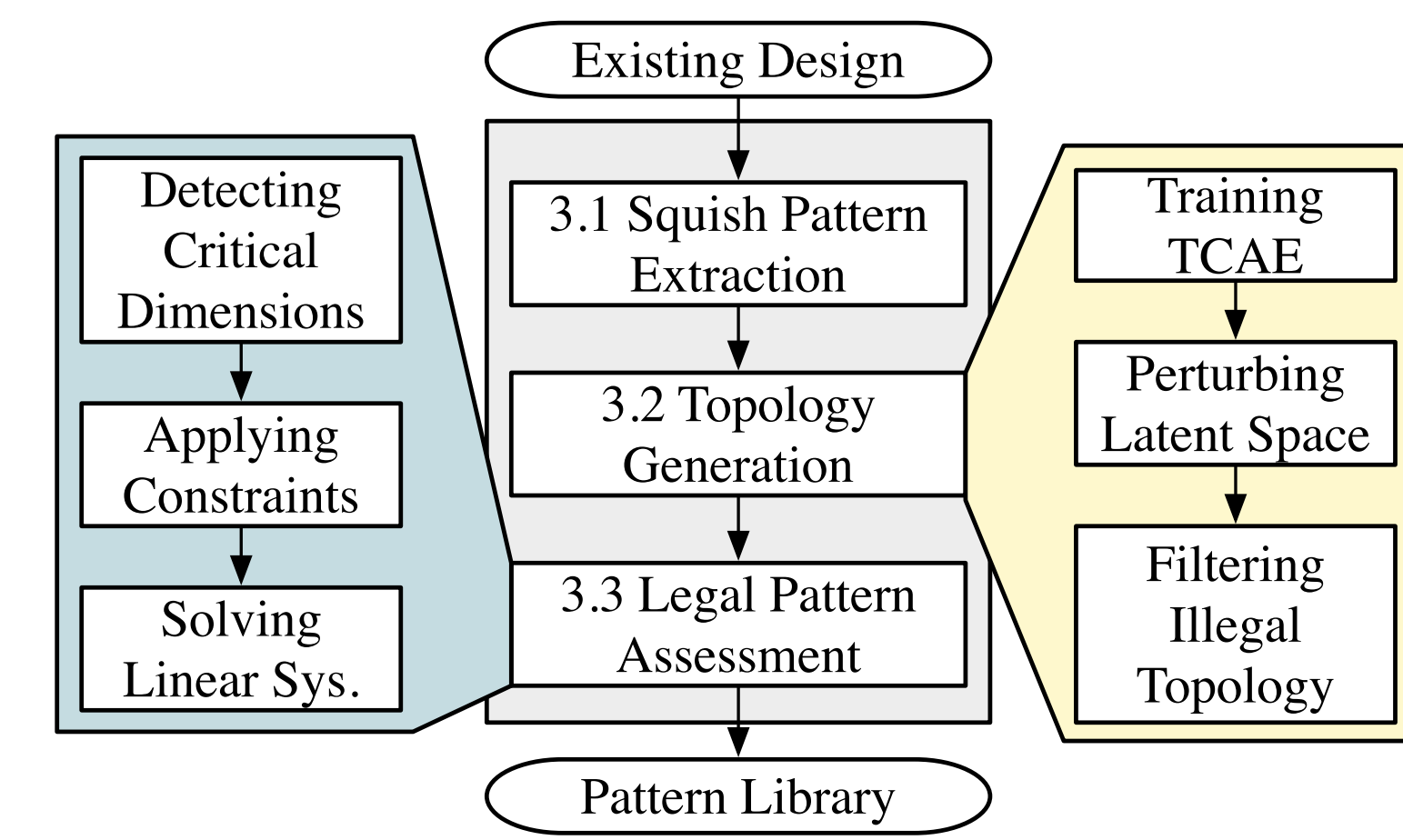
- Scan line-based representation, naturally supports easy computation of pattern complexity.
- Lossless feature representation.
- Easily feed into convolutional neural networks.

Problem Simplification

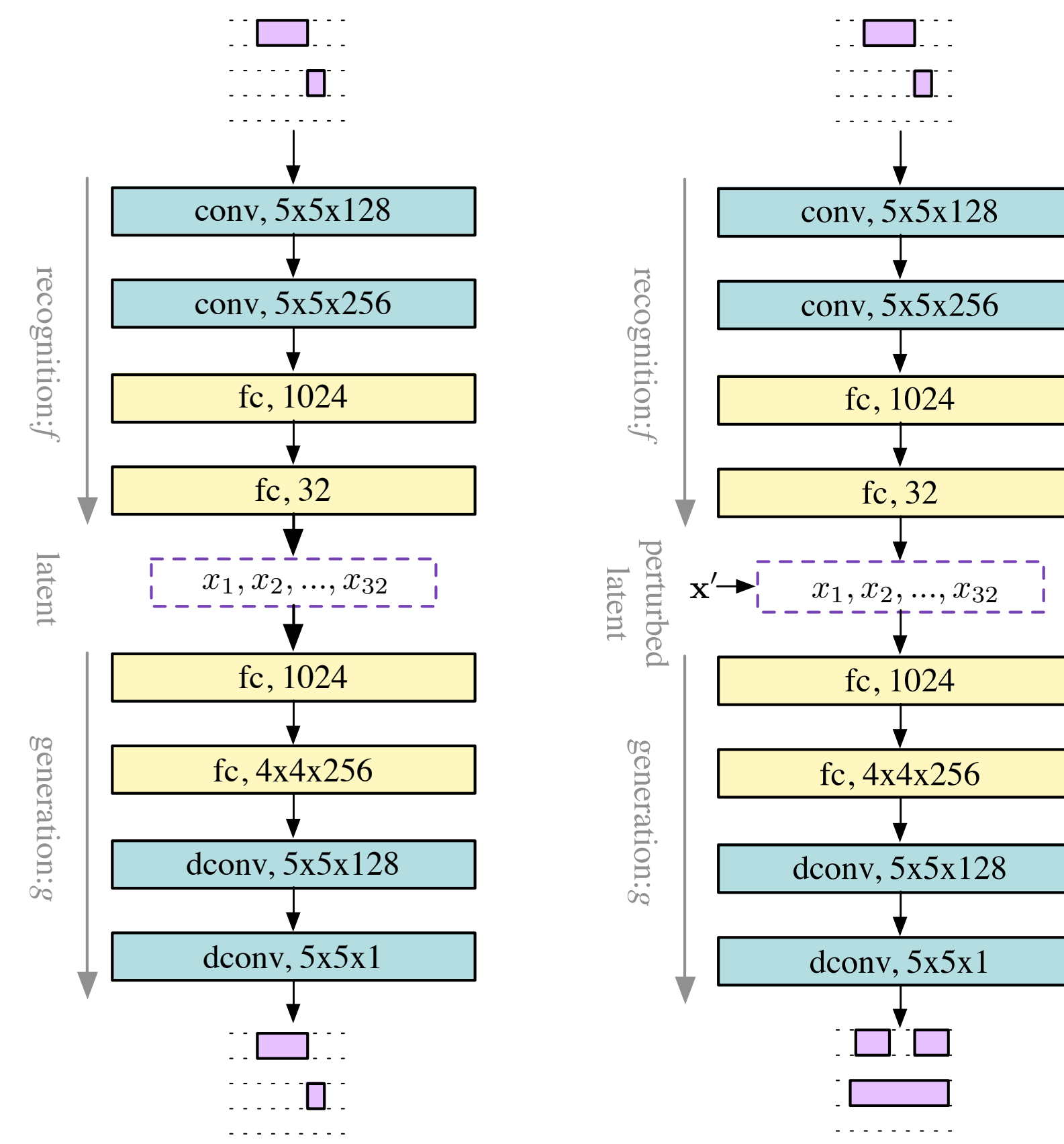
- Legal topology generation.
- Solving geometry constraints for DRC-clean patterns.

Methods

The Overall Flow



Transforming Convolutional Auto-Encoder



Input pattern to latent space,

$$I = f(T; W_f)$$

Topology reconstruction,

$$T' = g(I + \Delta I; W_g)$$

Training objective,

$$\min_{W_f, W_g} \|T - T'\|, \text{ s.t. } \Delta I = 0$$

- Inspired from TAE. [Hinton+, ICANN'11]
- Feature instantiation attains data set domain properties.
- All capsules contribute together to produce variations of any input objects.
- The transformation in our framework applies directly on the latent vector space that promises a much larger diversity of the generated patterns compared to the limited transformation on the coordinate system only in TAEs.
- Identity mapping in the training phase helps the TCAE capture the design rule properties of existing patterns.

Perturbing the Latent Space

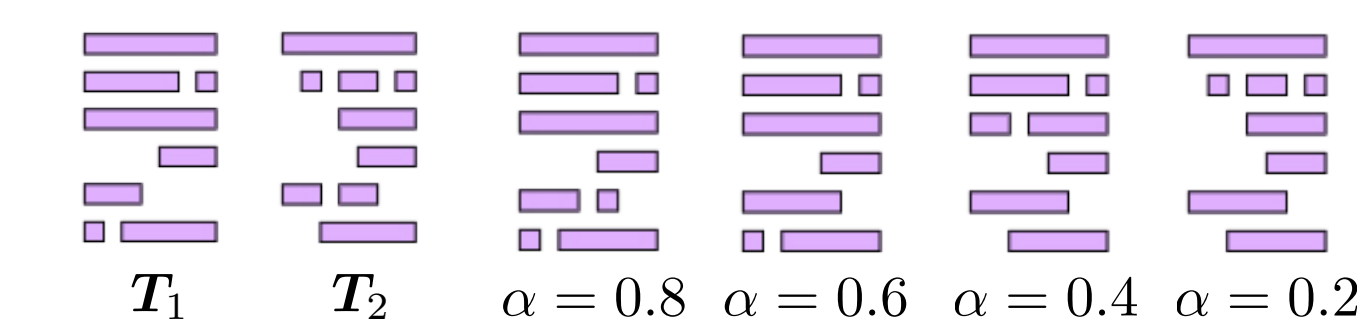
TCAE-Combine

- Generalization from existing topologies

$$T_g = g(\sum_i \alpha_i f(T_i)),$$

where $0 < \alpha_i < 1, \forall i$ are combination coefficients and satisfy $\sum_i \alpha_i = 1$.

- Sample results



TCAE-Random

- Introducing random perturbation from certain distribution randomly

$$T_g = g(f(T_i) + \Delta x),$$

where $\Delta x \sim \mathcal{N}$.

- Feature Sensitivity.** Let $I = [I_1 I_2 \dots I_n]^T$ be the output of the layer associated with the latent vector space. The sensitivity s_i of a latent vector node I_i is defined as the probability of reconstructed pattern being invalid when a perturbation $\Delta I_i \in [-t, t]$ is added up on I_i with everything else unchanged.

Legal Pattern Assessment

Creating DRC constraints for legal δ_x s and δ_y s,

$$\begin{aligned} y_{i+1} - y_i &= \frac{p}{2}, \\ x_i - x_j &= t_{\min}, \\ x_i - x_j &= l_{\min}, \\ x_{i+1} - x_i &> 0, \\ x_{\max} - x_0 &= d_x, y_{\max} - y_0 = d_y. \end{aligned}$$

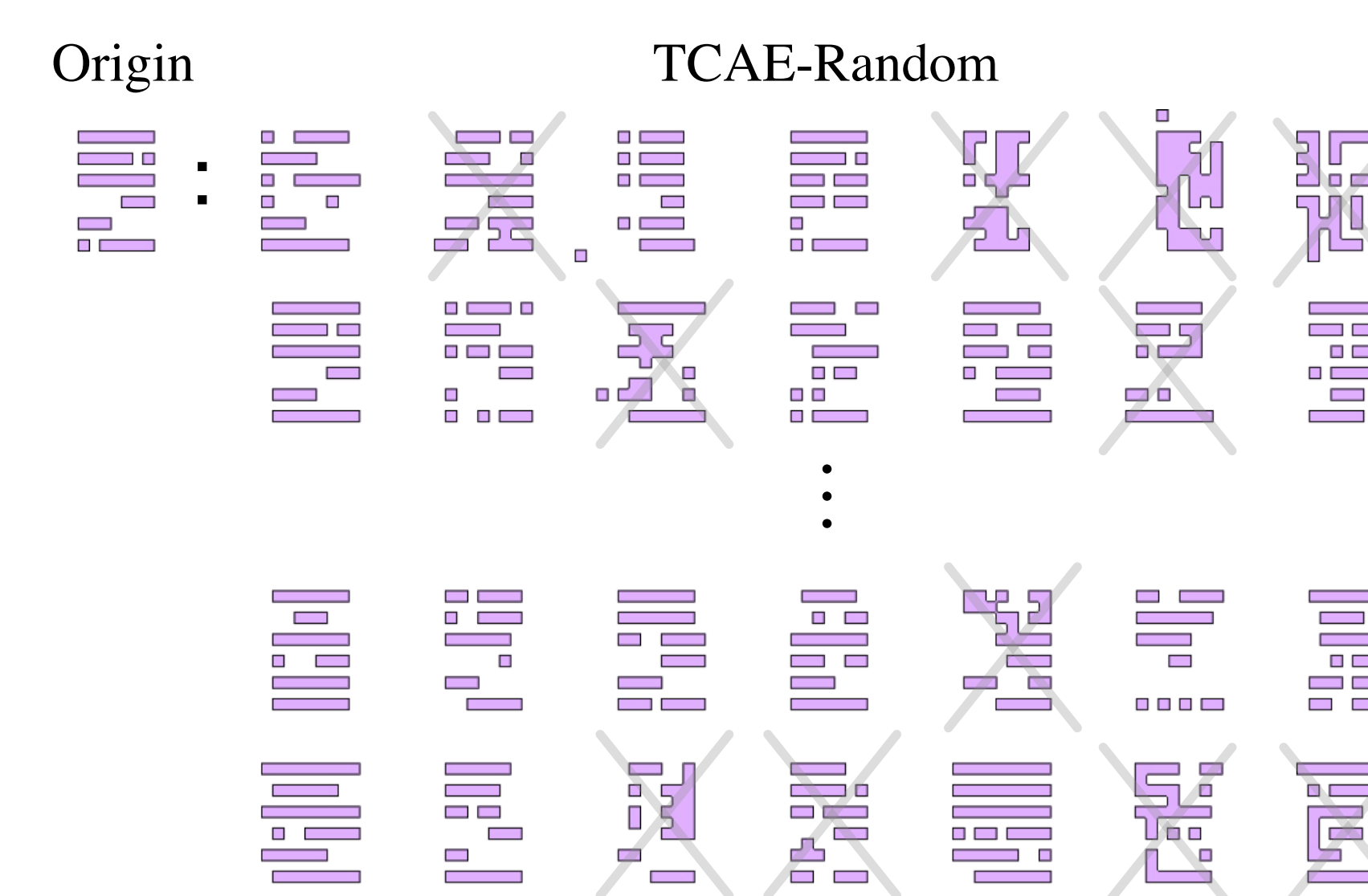
$$\begin{aligned} \forall i, \\ \forall (i, j) \in C_{T2T}, \\ \forall (i, j) \in C_W, \\ \forall i, \end{aligned}$$

Results and Conclusion

Understanding Features in TCAE

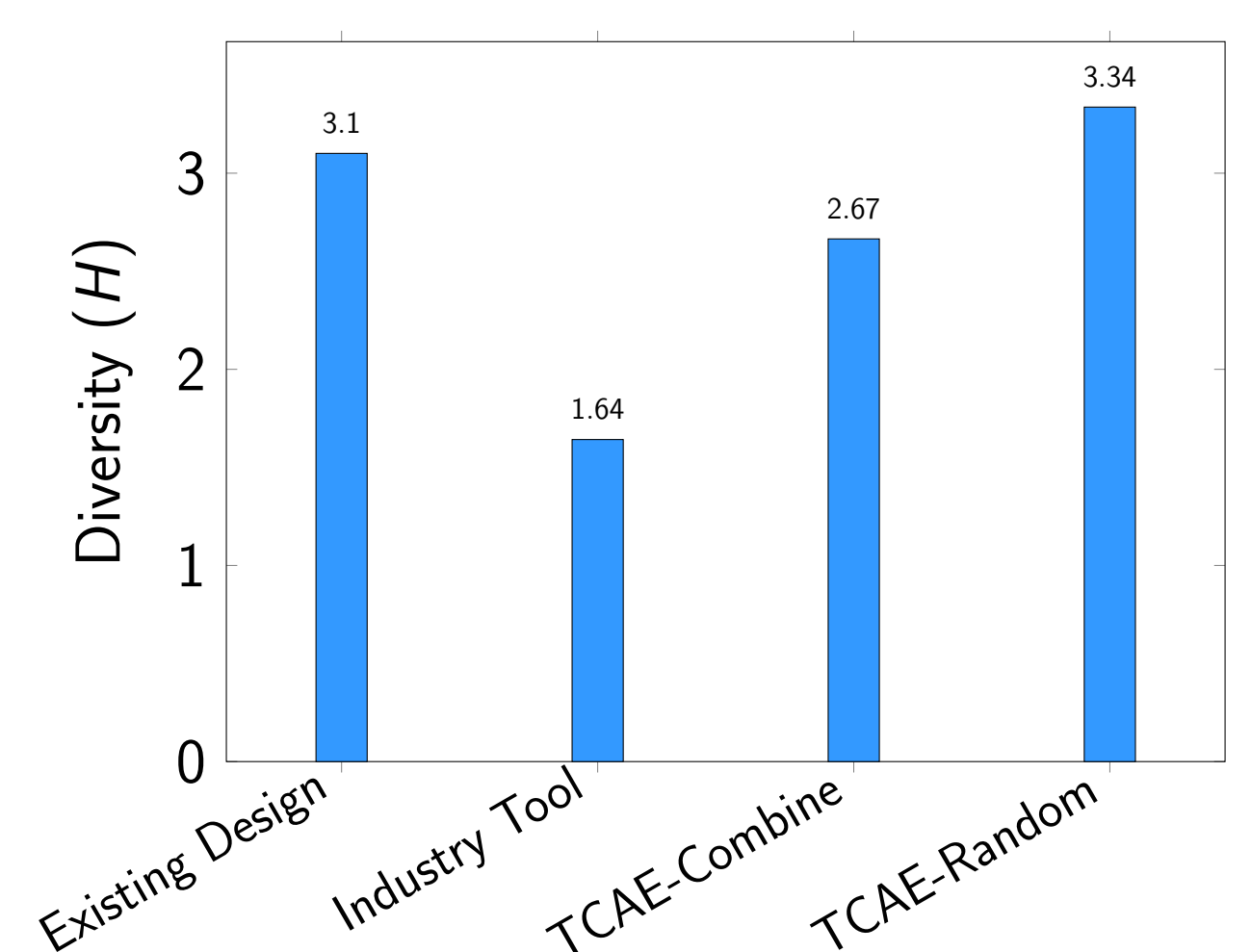
Transformations	Reconstructed Topologies
Extend or pull back line-ends	
Create or destroy shapes	
Control shape directions	

TCAE-Random



Comparison with State-of-the-Art

Perturbation with Gaussian exhibits greatest pattern generation power with around 30% generated patterns are unique and DRC clean.



Conclusion

- Address the pattern library requirements in DFM flows/researches under advanced technology nodes.
- Propose a TCAE framework that can capture layout design rule characteristics.
- We show auto-learned features contribute to layout space locally or globally.